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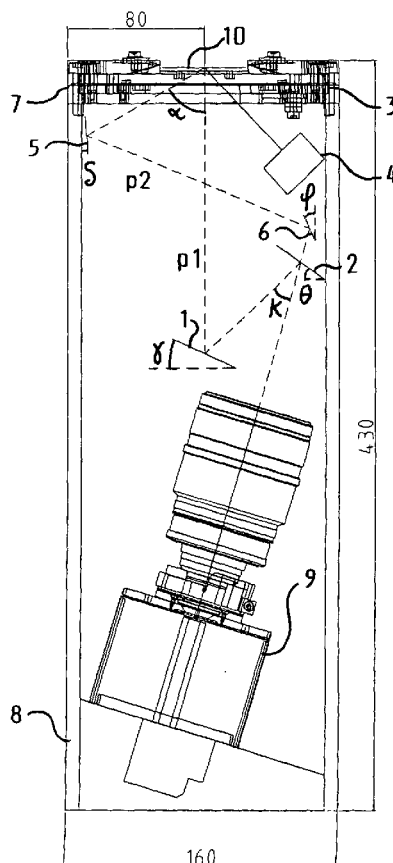
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(54) Title: A METHOD AND AN APPARATUS FOR MEASURING POSITIONS OF CONTACT ELEMENTS OF AN ELECTRONIC COMPONENT



(57) Abstract: A method and an apparatus for measuring respective positions of a set of N contact elements of an electronic component. A first and a second light path are created by a first and a second light beam which have different viewing angles. Both the first and the second light path can selectively be opened and both end into the image plane of a single camera. The positions being determined by using the first and second image produced by the first and second light beam respectively.



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